

**Extra Large Multi-DUT Array Probing  
enabling  
> X100 Parallel Testing**

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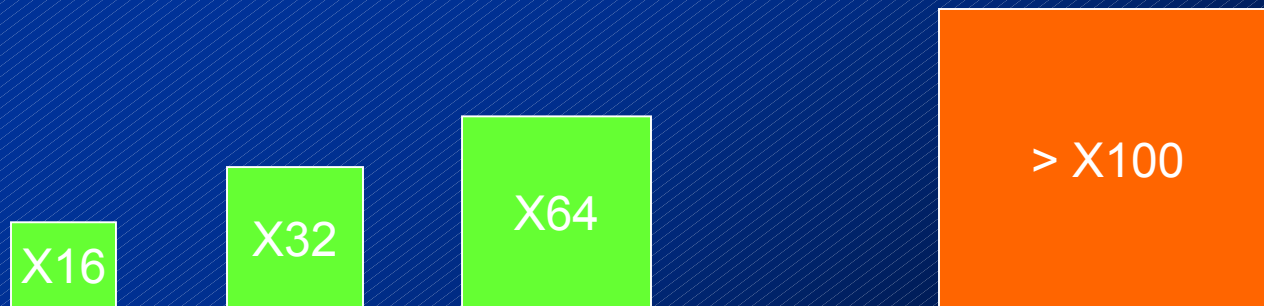


# Agenda

- **Introduction**
- **Motivation**
- **Challenges**
- **Preliminary Results**
- **Conclusions**
- **Acknowledgments**

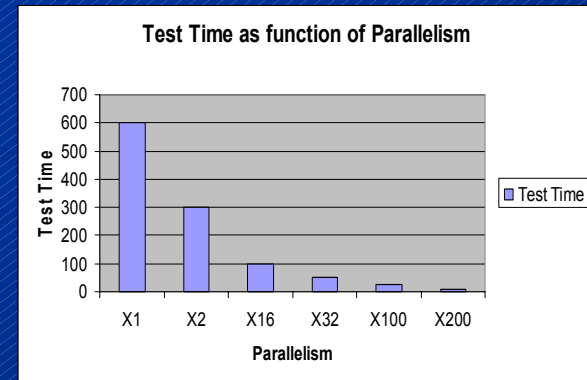
# 'XL Multi-DUT Probe-Card'

- **Multi-DUT: Multi – Device-Under-Test, which is also defined as 'Die Parallel' testing method.**
- **Probe-Card: Interface unit between Wafer/Die on Wafer and Test System.**
- **Why XL ?**
  - Flash Industry use X16 / X32 / X64 parallelism testing which is considered as standard.



# Motivation behind Multi-DUT testing

- **Reduced Wafer Test Time:**
  - Reduction in number of steps required to test a wafer
- **Increased test Output:**
  - Wafer throughput increase
- **Decrease in Probe-Card and Tester Inventory**

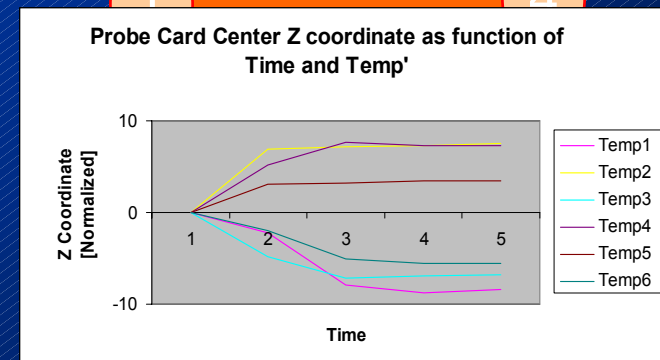
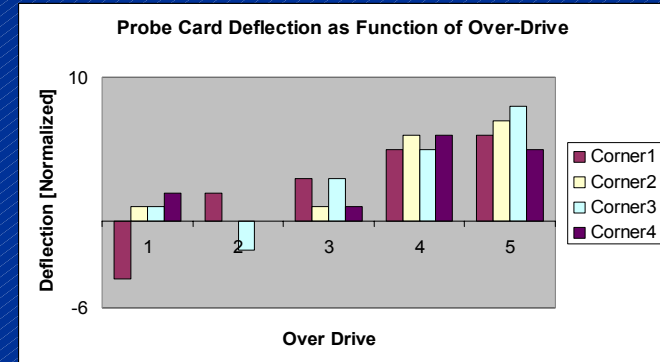


# **XL Multi-DUT Probe Card Challenges**

- **Probing Process**
- **Metrology Technology**
  - Existence & Capability
- **Repair & Maintenance**
- **Tester capability**
  - Channel count , Parallelism and S/W
- **Automation**
  - Support systems
- **Advanced Process Control**

# XL Multi-DUT Probing Challenges

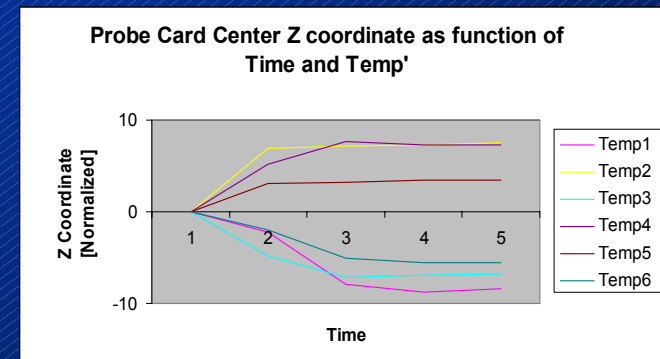
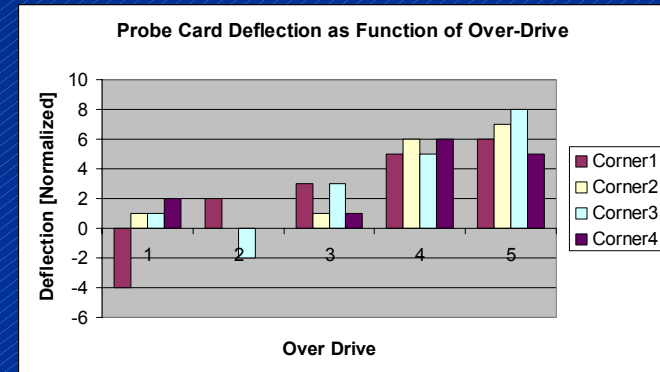
- **Very large effective probing area :**
  - Requirement for a large area contact uniformity through control of Alignment , Planarity and Test-Head deflections.
- **High thermal sensitivity:**
  - Probe-Cards have to be operational within the required Temp' Range of test.





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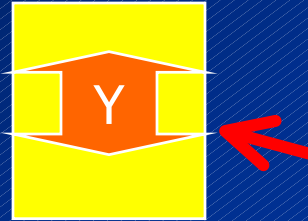


# XL Multi-DUT Probing Challenges:

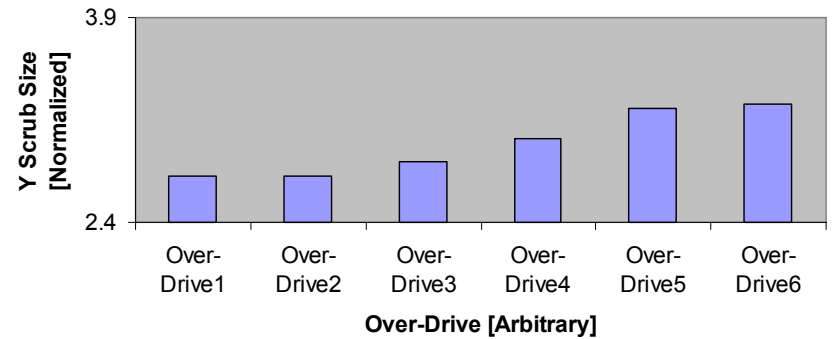
- **Probing Over-Drive:**
  - Characterizing the best value which achieves **Lowest Contact-Resistance & Pad Damage.**
- **Probe-Card Durability:**
  - Probe-Card & Process characteristics are to remain within given value window all through probe-card life time.



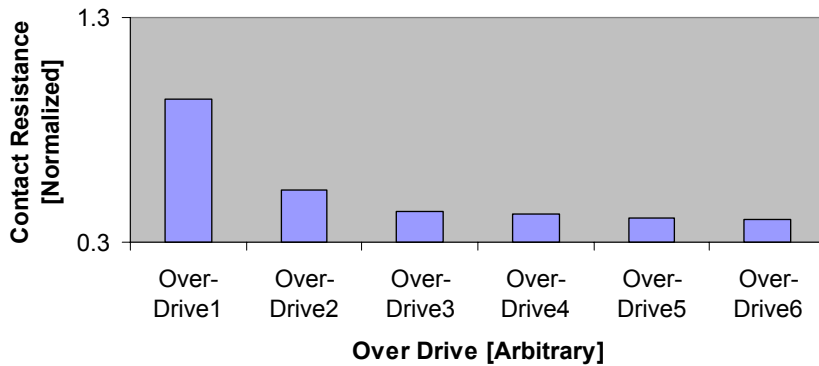
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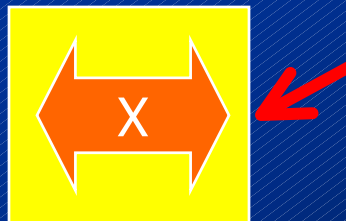
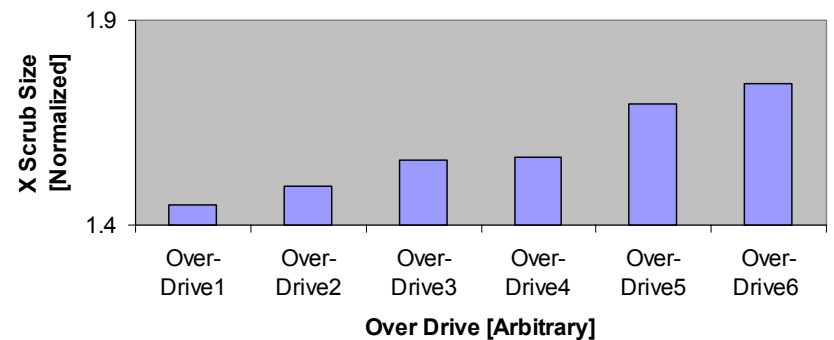
Y Scrub Size as Function of Over-Drive



Contact Resistance as Function of Over Drive

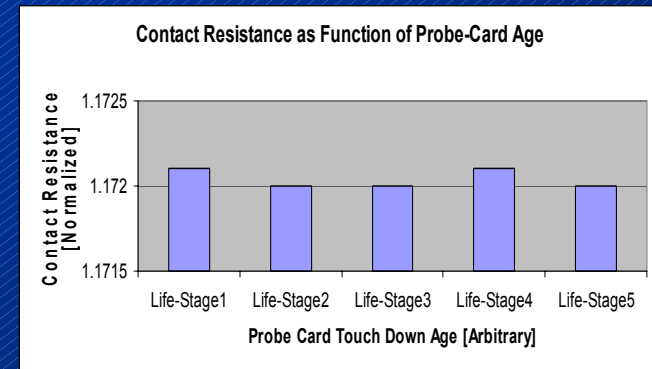


X Scrub Size as Function of Over Drive



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# Summary

- **Flash Like XRam test evolution drive a need for ever increasing parallel testing.**
- **'XL Multi-DUT Probing' brings many challenges.**
- **Key challenges where Identified and Mitigated.**
- **Preliminary data have shown promising results.**
- **More work is needed to understand process characteristics.**

# Acknowledgment

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